

Samenvatting Multi-axis microstage

Publicaties:

Resultaten, Multi-as microstage met subnanometer resolutie, IOP

<http://precisieportaal.nl/preciesimatrix/details.aspx?id=571>

<http://nvpt.nl/preciesimatrix/details.aspx?id=891>

Brouwer, Dannis Michel (2007) Design principles for six degrees-of-freedom MEMS-based precision manipulators,

<http://doc.utwente.nl/57871/>

Jong de, Boudewijn Ruben (2006) A six degrees of freedom MEMS manipulator.

<http://doc.utwente.nl/57599/>

D.M. Brouwer, B.R. De Jong, and H.M.J.R. Soemers, Design and modeling of a precision 6 degrees-of-freedom MEMS-based parallel kinematic TEM sample manipulator, ASPE, Monterey, California, USA, p. Session VIII, 2006, pp. 115-118

D. M. Brouwer, B.R. de Jong, M. J. de Boer, H.M.J.R. Soemers, Rotational precision MEMS-based Clamping Mechanism for stable fixation of Elastic Mechanisms, ASPE, Monterey, California, USA, 2006, pp.275-278

D.M. Brouwer, B.R. de Jong, H.M.J.R. Soemers, G.J.M. Krijnen, Numerical evaluation of piezo, thermo, electro-magnetic and electro-static MEMS actuators based on designs, EUSPEN Conference Baden bei Wien, Oostenrijk, mei 2006, pp. 172-175 (Keynote paper)

D.M. Brouwer, et al., 2006, MEMS-based 6 DOF parallel kinematic precision micro manipulator, EUSPEN Conference, Baden bei Wien, Oostenrijk, mei 2006, pp 111-114

D.M. Brouwer, B.R. de Jong, H.M.J.R. Soemers, Sub-nanometer stable precision MEMS clamping mechanism maintaining clamp force unpowered for TEM application, Journal of Micromechanics and Microengineering, 16, 2006, pp.7-12

D.M. Brouwer, B.R. de Jong, H.M.J.R. Soemers, J. Van Dijk, Sub-nanometer stable precision MEMS clamping mechanism maintaining clamp force un-powered for TEM application, Micromechanics and Microengineering Workshop, Gothenburg, sept 2005

B. R. De Jong, D. M. Brouwer, H. V. Jansen, M. J. De Boer, T. G. Lammertink, S. Stramigioli, and G. J. M. Krijnen, A planar 3 DOF sample manipulator for nano-scale characterization, in MEMS, (Istanbul, Turkey), pp. 750–753, 2006

B.R. de Jong, D.M. Brouwer, et al., Nanometer resolution TEM sample manipulator for rotational and translational positioning, Eurosensors 2005, TP43, Barcelona, Spain

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